



SEC.760

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Seung-pil Chung et al.

Group Art Unit: 1763

Serial No.: 09/689,814

Examiner: L. Alejandro Mulero

Filed: 13 October 2000

METHOD FOR REMOVING OXIDE
LAYER AND SEMICONDUCTOR
MANUFACTURING APPARATUS
FOR REMOVING OXIDE LAYER

H12B
4/15/03
mw

AMENDMENT UNDER 37 C.F.R. § 1.116

Honorable Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated 20 December 2002, and concurrent with
the Request for Continued Examination under 37 C.F.R. § 1.114 filed herewith,
please amend the above-identified patent application as follows:

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TC 1700

IN THE CLAIMS:

Please substitute the following claims for the pending claims with the same
claim numbers.

7. (Amended) A semiconductor manufacturing apparatus for use in removing
an oxide layer, comprising:
a vertically movable susceptor installed at a lower portion of a processing